

## Accepted Manuscript

Title: Jet electrochemical machining of micro dimples with conductive mask

Authors: X.L. Chen, B.Y. Dong, C.Y. Zhang, M. Wu, Z.N. Guo

PII: S0924-0136(18)30091-8  
DOI: <https://doi.org/10.1016/j.jmatprotec.2018.02.035>  
Reference: PROTEC 15662

To appear in: *Journal of Materials Processing Technology*

Received date: 6-11-2017  
Revised date: 29-1-2018  
Accepted date: 22-2-2018

Please cite this article as: Chen XL, Dong BY, Zhang CY, Wu M, Guo ZN, Jet electrochemical machining of micro dimples with conductive mask, *Journal of Materials Processing Technology* (2010), <https://doi.org/10.1016/j.jmatprotec.2018.02.035>

This is a PDF file of an unedited manuscript that has been accepted for publication. As a service to our customers we are providing this early version of the manuscript. The manuscript will undergo copyediting, typesetting, and review of the resulting proof before it is published in its final form. Please note that during the production process errors may be discovered which could affect the content, and all legal disclaimers that apply to the journal pertain.



**Jet electrochemical machining of micro dimples with conductive mask**

X.L. Chen <sup>a,b,\*</sup>, B.Y. Dong <sup>a</sup>, C.Y. Zhang <sup>a</sup>, M. Wu <sup>a</sup>, Z.N. Guo <sup>a,b</sup>

<sup>a</sup> School of Electro-mechanical Engineering, Guangdong University of Technology, Guangzhou 510016, RP China

<sup>b</sup> Guangzhou Key Laboratory of Nontraditional Machining and Equipment, Guangzhou 510006, RP China

\* Corresponding author: X.L. Chen

Tel: 86-20-39322412; Fax: 86-20-39322412; E-mail: xlchen@gdut.edu.cn )

Download English Version:

<https://daneshyari.com/en/article/7176362>

Download Persian Version:

<https://daneshyari.com/article/7176362>

[Daneshyari.com](https://daneshyari.com)